

**TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT**  
**(Under 37 CFR 1.97(b) or 1.97(c))**

Docket No.  
**50T5690.01**

In Re Application Of: **Tenko Yamashita**

Serial No.  
**Unassigned**

Filing Date  
**Filed Herewith**

Examiner  
**Unassigned**

Group Art Unit  
**Unassigned**

Title: **SILICON-ON INSULATOR (SOI) SUBSTRATE HAVING DUAL SURFACE CRYSTALLOGRAPHIC ORIENTATIONS AND METHOD OF FORMING SAME**

Address to:  
**Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450**

**37 CFR 1.97(b)**

1. ☒ The Information Disclosure Statement submitted herewith is being filed within three months of the filing of a national application other than a continued prosecution application under 37 CFR 1.53(d); within three months of the date of entry of the national stage as set forth in 37 CFR 1.491 in an international application; before the mailing of a first Office Action on the merits, or before the mailing of a first Office Action after the filing of a request for continued examination under 37 CFR 1.114.

**37 CFR 1.97(c)**

2. ☐ The Information Disclosure Statement submitted herewith is being filed after the period specified in 37 CFR 1.97(b), provided that the Information Disclosure Statement is filed before the mailing date of a Final Action under 37 CFR 1.113, a Notice of Allowance under 37 CFR 1.311, or an Action that otherwise closes prosecution in the application, and is accompanied by one of:
- ☐ the statement specified in 37 CFR 1.97(e);
- OR**
- ☐ the fee set forth in 37 CFR 1.17(p).

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ORIENTATIONS AND METHOD OF FORMING SAME**

**Payment of Fee**

(Only complete if Applicant elects to pay the fee set forth in 37 CFR 1.17(p))

- ☐ A check in the amount of \_\_\_\_\_ is attached.
- ☒ The Director is hereby authorized to charge and credit Deposit Account No. **50-1047**  
as described below.
- ☐ Charge the amount of \_\_\_\_\_
- ☐ Credit any overpayment.
- ☒ Charge any additional fee required.

**Certificate of Transmission by Facsimile\***

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(Date)

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Signature

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**Certificate of Mailing by ~~First Class~~ Mail**

*EXPRESS*

I certify that this document and fee is being deposited  
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*Magnus Mariani*  
Signature of Person Mailing Correspondence

*MARJORIE SCARATI*  
Typed or Printed Name of Person Mailing Certificate

**\*This certificate may only be used if paying by  
deposit account.**

*Keum J. Park*  
Signature

Dated: *March 12, 2004*

Keum J. Park Reg. No. 42,059  
Mayer Fortkort & Williams, PC  
251 North Avenue West, 2nd Floor  
Westfield, NJ 07090

Tel.: 908-518-7700

CC:

(Use several sheets if necessary)

**50T5690.01**

## Unassigned

**Tenko Yamashita**

**Filed Herewith**

## Unassigned

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	1	Momose, H.S. et al., " <i>1.5-nm Gate Oxide CMOS on (110) Surface-Oriented Si Substrate</i> ," IEEE Transactions On Electron Devices, Vol. 50, No. 4, April 2003, pp. 1001-1008.

DATE CONSIDERED

**SHEET 1 OF 1**